Continuous Processing of Thin-Film Batteries and Like Devices

Abstract of the Disclosure

A system for making a thin-film device includes a substrate-supply station that supplies a substrate having a major surface area. The substrate has a first layer on a first surface area of the substrate's major surface area. Also included is a device for depositing a second layer onto the first layer, wherein the device supplies energy to the second layer to aid in layer formation without substantially heating the substrate.

"Express Mail" mailing label number: EL671638340US
Date of Deposit: March 23, 2001

This paper or fee is being deposited on the date indicated above with the United States Postal Service pursuant to 37 CFR 1.10, and is addressed to the Commissioner for Patents, Box Patent Application, Washington, D.C. 20231.